

SEMICONDUCTOR PROCESSING WITH A REMOTE PLASMA
SOURCE FOR SELF-CLEANING

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Appl. No.: Unknown Atty Docket: ASMJP.055C1

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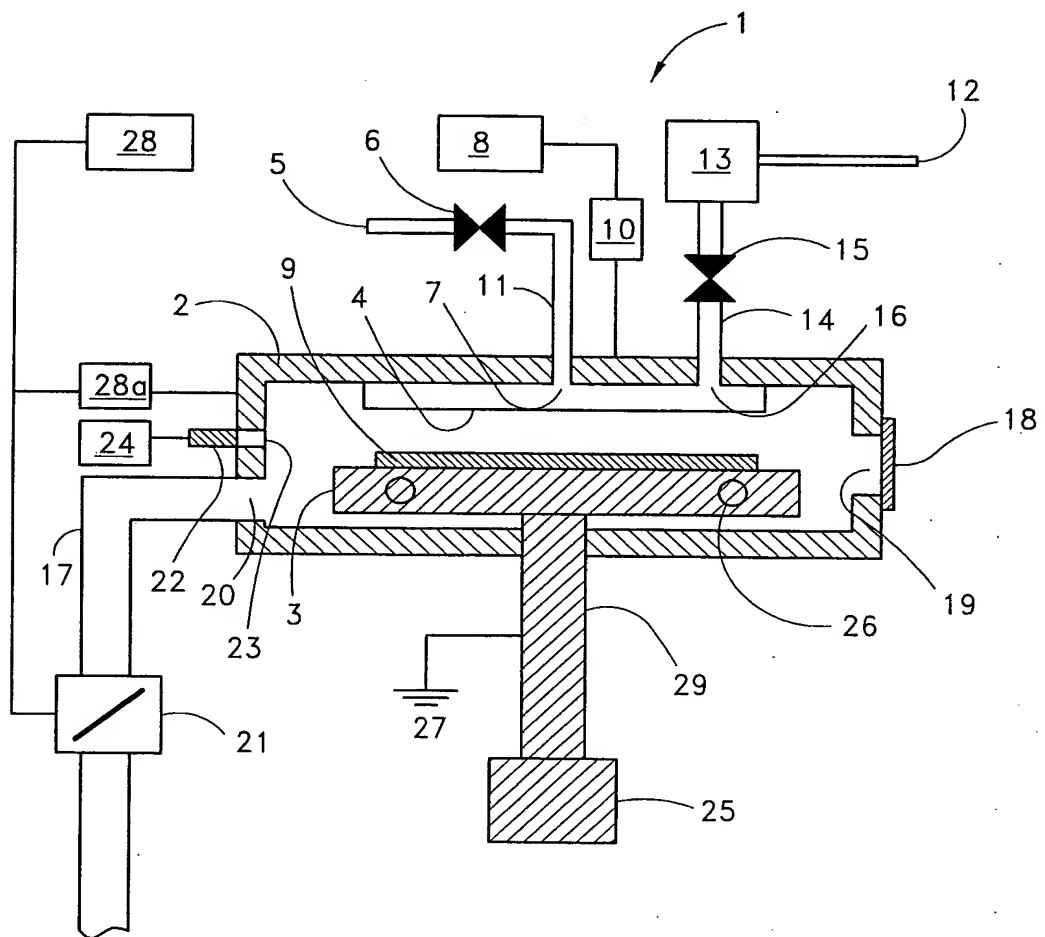


FIG. 1

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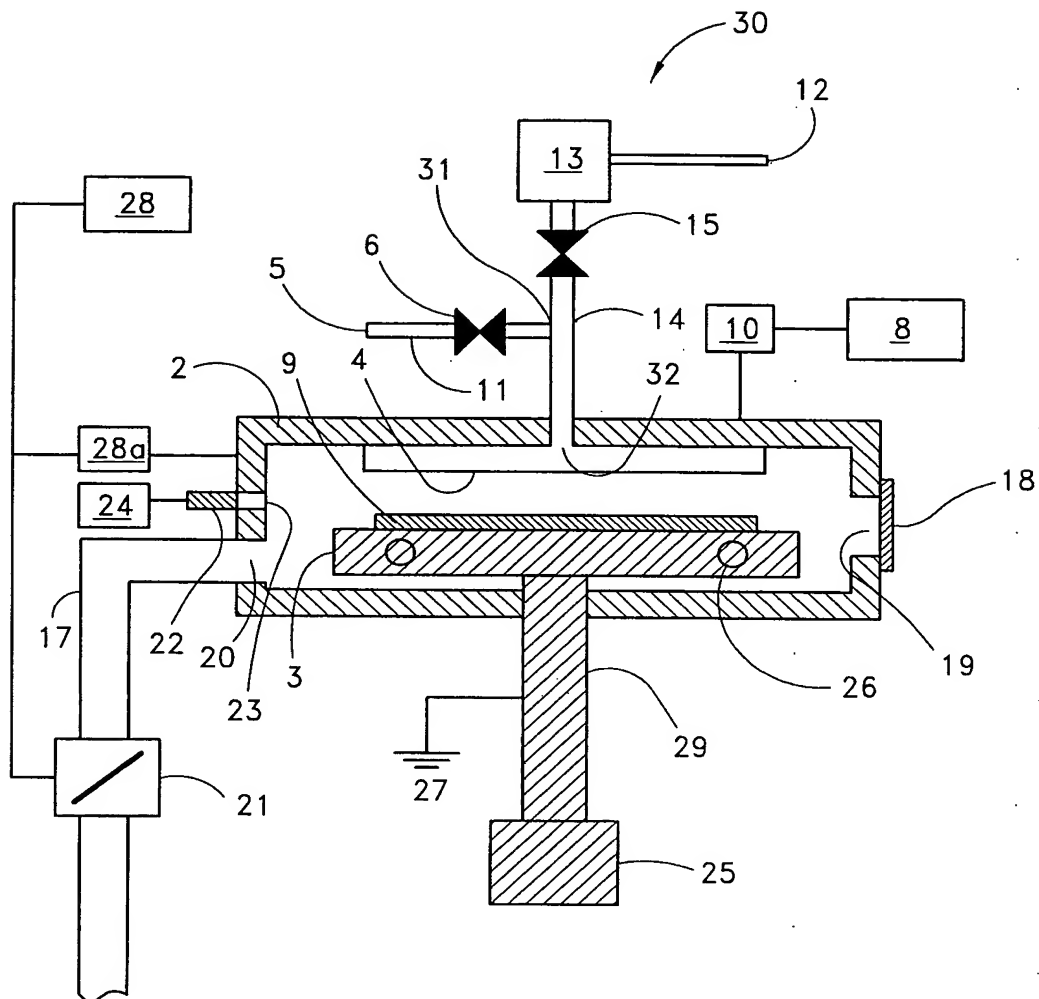


FIG. 2

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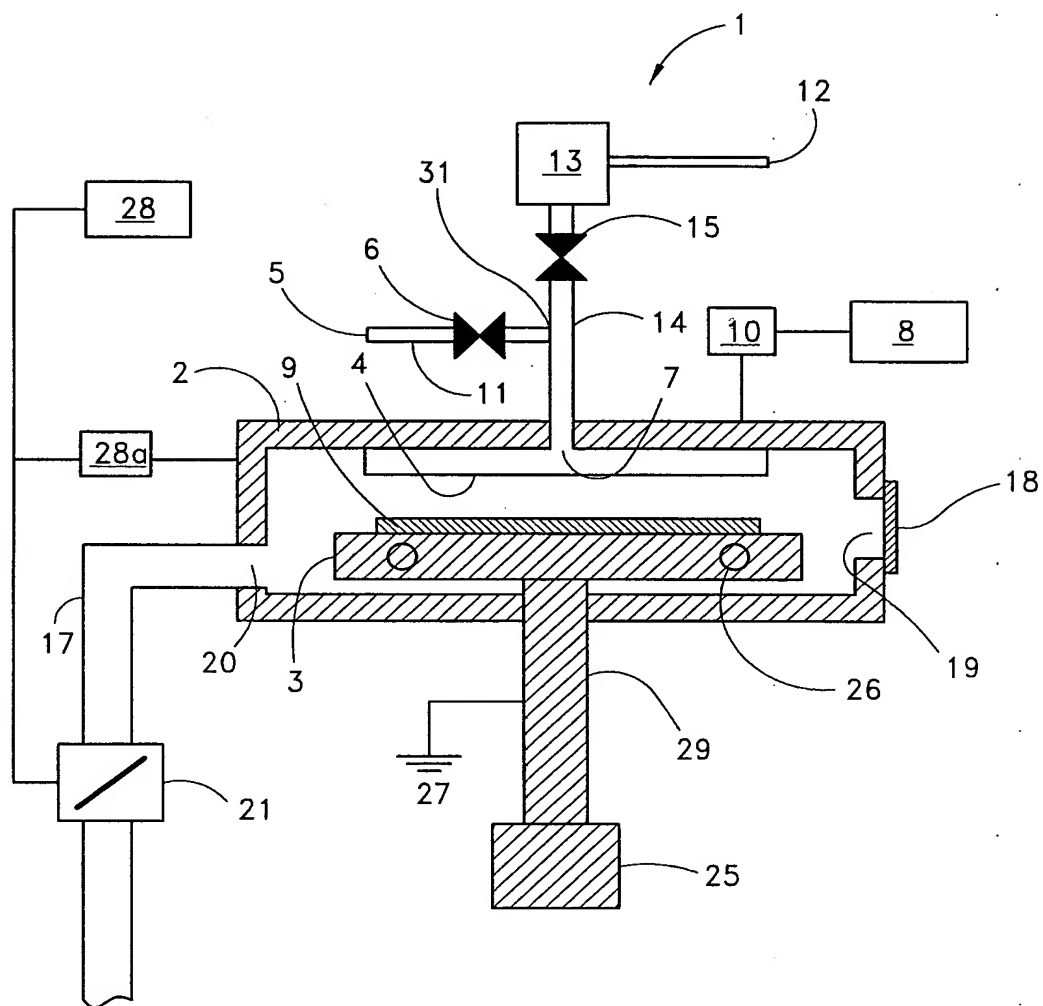


FIG. 3

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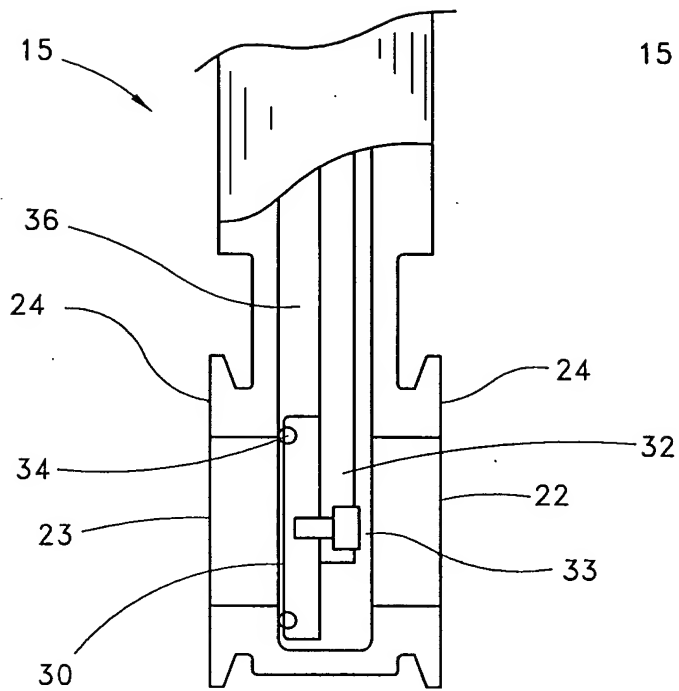


FIG. 4A

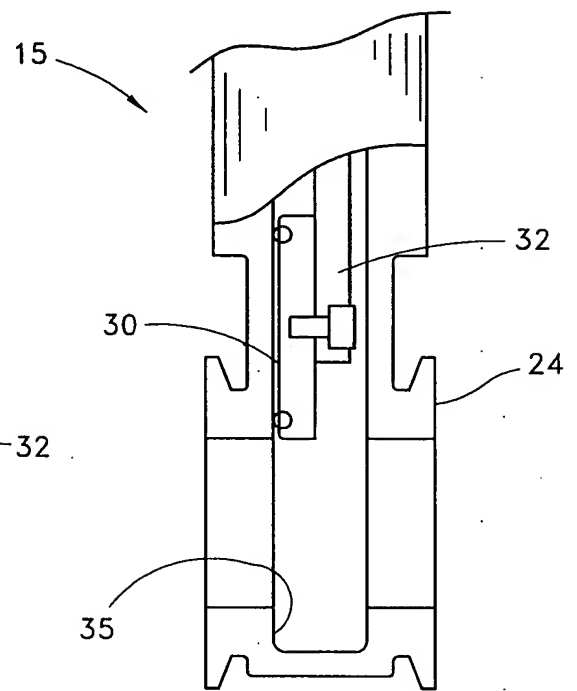


FIG. 4B

